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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

re application of:

Group Art Unit: 1725

Bo Gu, et al.

Examiner:

Serial No.: 10/787,517

Filed: February 26, 2004

For: LASER SYSTEM AND METHOD FOR MATERIAL
PROCESSING WITH ULTRA FAST LASERS

Attorney Docket No.: GSIL 0191 PUSP

**INFORMATION DISCLOSURE STATEMENT
UNDER 37 C.F.R. § 1.97(b)**

Mail Stop Amendment
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Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and §§ 1.97-1.98, the references listed and identified on the attached Forms PTO/SB08A and/or SB08B are being submitted herewith for consideration by the Examiner. This Statement is being filed in accordance with 37 C.F.R. § 1.97(b).

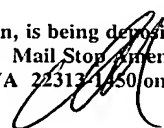
While this Statement is being filed in compliance with the duty of disclosure, citation of the listed references is not to be construed as an admission that any of the references are "material" as defined under 37 C.F.R. § 1.56(b).

CERTIFICATE OF MAILING UNDER 37 C.F.R. § 1.8

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Signature

No copies of the listed U.S. patent references or the listed U.S. patent application publication references have been included herewith pursuant to 37 C.F.R. § 1.98(a)(2). Consideration and entry into the record of the listed references is respectfully requested.

Respectfully submitted,

Bo Gu, et al.

By: 

David R. Syrowik
Reg. No. 27,956
Attorney/Agent for Applicant

Date: December 14, 2004

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Substitute for Form 1449A/PTO

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(use as many sheets as necessary)

Complete if Known

Application Number	10/787,517
Filing Date	February 26, 2004
First Named Inventor	Bo Gu, et al.
Group Art Unit	1725
Examiner Name	
Attorney Docket Number	GSIL 0191 PUSP

Sheet	1	of	3
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U.S. PATENT DOCUMENTS

[illegible]

FOREIGN PATENT DOCUMENTS

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Examiner Signature		Date Considered	
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Substitute for Form 1449B/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>			Complete if Known		
			Application Number	10/787,517	
			Filing Date	February 26, 2004	
			First Named Inventor	Bo Gu, et al.	
			Group Art Unit	1725	
			Examiner Name		
Sheet	2	of	3	Attorney Docket Number	GSIL 0191 PUSP

OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS

Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
		KRUGER, ET AL., Femtosecond-Pulse Laser Processing of Metallic and Semiconducting Thin Films, PROC. SPIE, Vol. 2403, 1995, pp. 436-447	
		CHICHKOV, ET AL., Femtosecond, Picosecond, and Nanosecond Laser Ablation of Solids, APPLIED PHYSICS, A 63, 1996, pp. 109-115	
		STUART, ET AL., Ultrashort-Pulse Optical Damage, PROC. SPIE, Vol. 2714, 1996, pp. 616-629	
		HAIGHT, ET AL., Implementation and Performance of a Femtosecond Laser Mask Repair System in Manufacturing, 1998, pp. 1-8,	
		ISLAM, ET AL., On Ultrashort Laser Pulse Machining, TECHNICAL REPORT, 1998.	
		ZHAO, ET AL., Micromachining with Ultrashort Laser Pulses, PROC. SPIE, Vol. 3618, 1999, pp. 114-121	
		ZHU, ET AL., Influence of Laser Parameters and Material Properties on Micro-Drilling with Femtosecond Pulses, APPLIED PHYSICS A69 [Suppl], 1999, 367-S371	
		TONSHOFF, ET AL., Micromachining Using Femtosecond Lasers, LPM 2000 CONFERENCE, Japan, June 2000, pp. 1-15.	
		PERRY, ET AL., Ultrashort-Pulse Laser Machining, LIA HANDBOOK OF LASER MATERIALS PROCESSING, Ed. In Chief Ready, Laser Institute of America, 2001, pp. 499-508	
		PERRY, ET AL., Ultrafast Lasers for Material Processing, LIA HANDBOOK OF LASER MATERIALS PROCESSING, Ed. In Chief Ready, Laser Institute of America, 2001, p. 82	
		LIU, XINBING, ET AL., Ultrashort Laser Pulses Tackle Precision Machining, Laser Focus World, August 1997.	
		JANDELEIT, J., ET AL., Picosecond Laser Ablation of Thin Copper Films, Applied Physics A 63, 1996, pp. 117-121.	

Examiner Signature		Date Considered	
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹Unique citation designation number. ²Applicant is to place a check mark here if English language Translation is attached.

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		STUART, B.C., ET AL., Optical Ablation By High-Power Short-Pulse Lasers, Optical Society of AMERICA, VOL. 13, No. 2, February 1996, pp. 459-468.			
		AMEER-BEG, S., ET AL., Femtosecond Laser Microstructuring of Materials, Applied Surface Science 127-129, 1998, pp. 875-880.			
		SUCHA, GREGG, Doped Optical Fibers Promise Compact FEMTOSECOND Sources, Laser Focus World, 1998, pp. 1-4.			
		NOLTE, S., ET AL., Ablation of Metals by Ultrasort Laser Pulses, Optical Society of America, B/Vol. 10, October 1997, pp. 2716-2722.			
		KAUTEK, WOLFGANG, ET AL., Femtosecond Pulse Laser ABLATION OF METALLIC, Semiconducting, Ceramic, and Biological Materials, SPIE Vol. 2207, pp. 600-611.			
		CORKUM, P.B., ET AL., Thermal Response of Metals to Ultrashort-PULSE Laser Excitation, The America Physical Society, December 19, 1988, Vol. 61, No. 25, pp. 2886-2889.			
		LIU, HSIAO-HUA, ET AL., Effects of Wavelength and Doping Concentration on Silicon Damage Threshold, pp. 1-2.			
		KORTE, F., ET AL., Nanostructuring With Femtosecond Laser PULSES, CLEO, 2000, PP. 374.			

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